

Oxygen transport in thin oxide films at high field strength

Dieter Weber

Forschungszentrum Jülich GmbH
Peter Grünberg Institute (PGI)
Microstructure Research (PGI-5)

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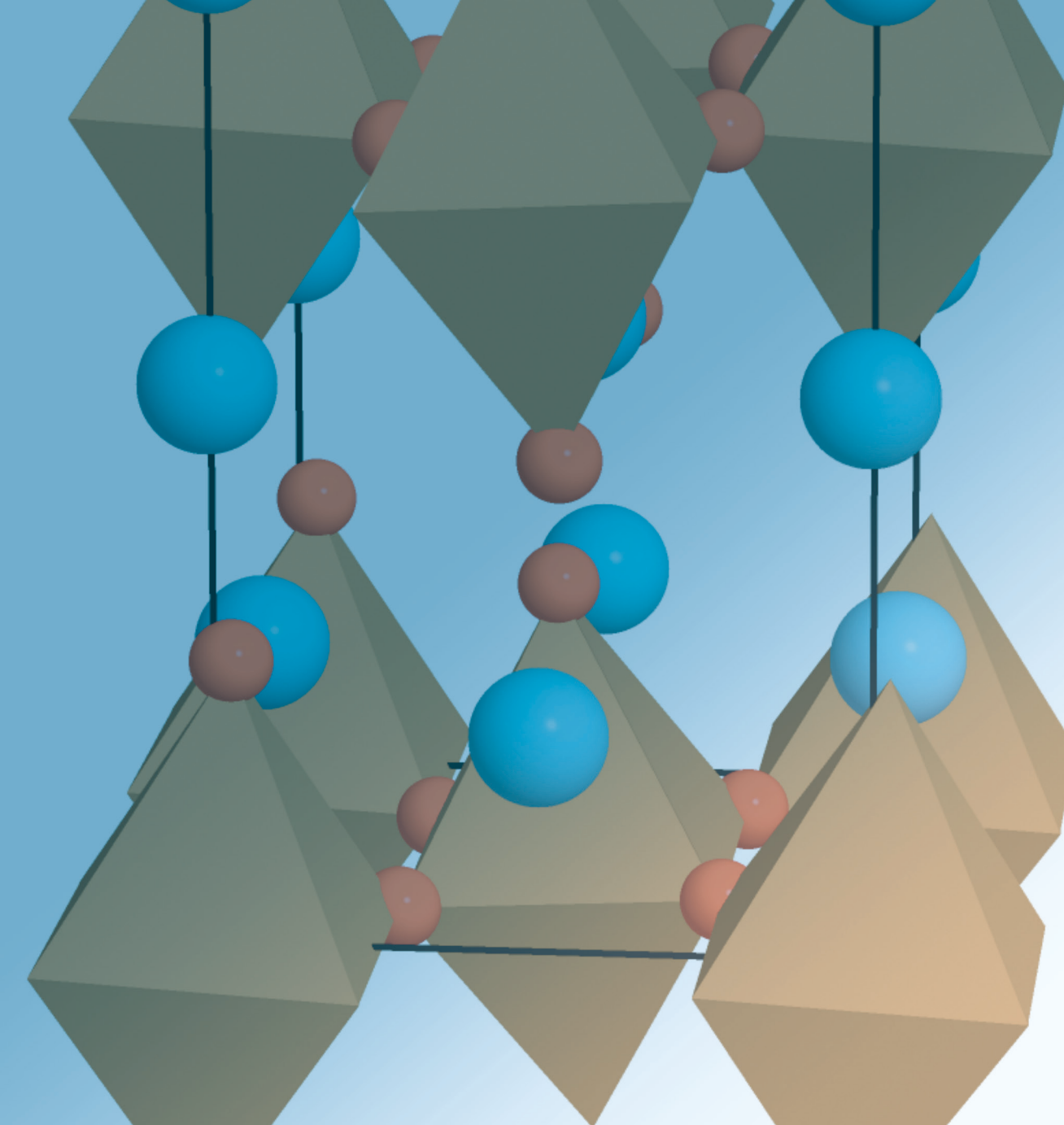
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